

A PROBE TIP AND METHOD OF MANUFACTURING TIPS AND PROBES FOR  
DETECTING MICROCURRENT OR MICROFORCE

Abstract of the Disclosure

5 [0056] A full metal probe and a method of making the  
metal probe for electrical atomic force microscopy. In one  
embodiment, the method comprises manufacturing the full metal  
probe using two lithography steps. The step of etching thin  
membranes is dropped or eliminated to substantially reduce  
10 the processing time. Thus, topside processing is sufficient.  
The probe and tip can be peeled off from the wafer using a  
metallisation procedure.

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